

PATENT ABSTRACTS OF JAPAN

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(54) PROBE CARD

(57)Abstract:

PROBLEM TO BE SOLVED: To obtain a probe card in which a change in the height position of a needle retainer is reduced even when a substrate is thermally deformed by a method wherein a support plate is fixed to the surface of the substrate and the needle retainer is fixed to the rear surface of the support plate.

SOLUTION: A support plate 42 is fixed to the surface of a substrate 36, and a needle retainer 32 is fixed to the rear surface of the support plate 42. The needle retainer 32 protrudes to the lower part from a rectangular substrate through hole 38 in the central part of the substrate 36. The position of a tightening device 44 which fixes the substrate 36 to the support plate 42 is situated on the outer circumferential side of the substrate 36 from the position of a tightening device 40 which fixes the support plate 42 to the needle retainer 32. A rectangular needle-retainer through hole 46 and a support-plate through hole 48 which are nearly of the same size are formed in the center of the needle retainer 32 and the support plate 42, and the contact state of a probe needle 30 with the electrode of the object to be inspected can be observed from the upper part by using a microscope or the like.

